

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent of:	)
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Natsuhiko MIZUTANI	) Examiner: M. Liu
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Application No.: 10/529,893	) Group Art Unit: 2851
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Filed: August 6, 2004	) Confirmation No.: 7796
	:
For: NEAR-FIELD EXPOSURE METHOD AND	) June 18, 2008
APPARATUS, NEAR-FIELD EXPOSURE MASK,:	)
AND DEVICE MANUFACTURING METHOD	)
	:
U.S. Patent No. 7,315,354 B2	)
	:
Issued: January 1, 2008	)

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
**Attention: Certificate of Correction Branch**

LETTER CALLING ATTENTION TO ERROR IN PATENT

Sir:

Patentee notes the following error in the above-identified patent:

COLUMN 12:

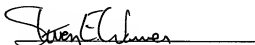
Line 15, "nesses" should read -- ness --.

This error is relatively insignificant. Therefore, Patentee believes that filing a Request for Certificate of Correction is not warranted. Rather, Patentee requests that this paper be placed of record in the official file of the subject patent.

Patentee believes no fee is due for filing this paper. Nevertheless, the Commissioner is authorized to charge Deposit Account No. 06-1205 should any fee be deemed required.

Patentee's undersigned attorney may be reached in our Washington, D.C. Office by telephone at (202) 530-1010. All correspondence should continue to be directed to our below-listed address.

Respectfully submitted,

  
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